Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L2	1	("6198976").PN.	US-PGPUB; USPAT	OR	OFF	2005/10/17 16:00
S1	0	(sens$3 with compar$3 with line with position$4 with (wafer substrate workpiece semiconductor)) and (118/715-733.ccls. 156/345.$.ccls. 414/935-941.ccls.)	US-PGPUB; USPAT	OR	ON	2004/08/08 17:30
S2	3	(compar$3 with line with position$4 with (wafer substrate workpiece semiconductor)) and (118/715-733.ccls. 156/345.$. ccls. 414/935-941.ccls.)	US-PGPUB; USPAT	OR	ON	2004/08/08 17:33
S3	206	(compar$3 with line with position$4 with (wafer substrate workpiece semiconductor))	US-PGPUB; USPAT	OR	ON	2004/08/08 17:31
S4	4	(compar$3 with line with position$4 with (wafer substrate workpiece semiconductor)) same (transfer$4 convey$4 transport$4)	US-PGPUB; USPAT	OR	ON	2004/08/08 17:33
S5	206	(compar$3 with line with position$4 with (wafer substrate workpiece semiconductor))	US-PGPUB; USPAT	OR	ON	2004/08/08 17:35
S6	3	(compar$3 with line with position$4 with (wafer substrate workpiece semiconductor)) same (transfer$4 convey$4 transport$4)	EPO; JPO; DERWENT	OR	ON	2004/08/08 17:33
S7	99	((sens$3 detect$3 measur$3) with compar$3 with line with position$4 with (wafer substrate workpiece semiconductor))	US-PGPUB; USPAT	OR	ON	2004/08/08 17:36
S8	105	((sens$3 detect$3 measur$3) with compar$3 with line with (align$4 position$4) with (wafer substrate workpiece semiconductor))	US-PGPUB; USPAT	OR	ON	2004/08/08 17:39
S9	321	(414/936).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/08/08 17:39
S10	244	S9 and (sens$3 detect$3)	US-PGPUB; USPAT	OR	ON	2004/08/08 17:40
S11	199	S9 and ((sens$3 detect$3) with (position$3 align$3))	US-PGPUB; USPAT	OR	ON	2004/08/08 17:40
S12	23	S9 and ((sens$3 detect$3) with (position$3 align$3) with compar$4)	US-PGPUB; USPAT	OR	ON	2004/08/08 17:40
S13	1819	((118/719) or (414/939) or (156/345.31) or (156/345.32)).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2004/08/08 17:28
S14	31	(((118/719) or (414/939) or (156/345.31) or (156/345.32)). CCLS.) and 156/345.24.ccls.	US-PGPUB; USPAT	OR	ON	2003/12/12 18:38
S15	322	(((118/719) or (414/939) or (156/345.31) or (156/345.32)). CCLS.) and ((position$3 align$4) with (detect$3 sens$3 monitor$3 sens$3))	US-PGPUB; USPAT	OR	ON	2003/12/12 18:39
S16	1757	(118/715-733.ccls. 156/345.$.ccls. 414/935-941.ccls.) and ((position$3 align$4) with (detect$3 sens$3 monitor$3 sens$3))	US-PGPUB; USPAT	OR	ON	2003/12/12 18:39
S17	43	(118/715-733.ccls. 156/345.$.ccls. 414/935-941.ccls.) and ((position$3 align$4) with (detect$3 sens$3 monitor$3 sens$3) with (inlet entry entrance))	US-PGPUB; USPAT	OR	ON	2003/12/12 18:40
S18	3	(("5483138") or ("5917601") or ("6004047")).PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2003/12/18 18:25
S19	1	("5512320").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2003/12/18 18:42
S20	1827	((118/719) or (414/939) or (156/345.31) or (156/345.32)).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2003/12/18 18:43
S21	331	(((118/719) or (414/939) or (156/345.31) or (156/345.32)). CCLS.) and ((position$3 align$3) with (sens$3 detect$3 monitor$3 observ$5))	US-PGPUB; USPAT	OR	ON	2003/12/18 19:36

S22	384	((156/345.13) or (156/345.15) or (156/345.24)).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2003/12/18 18:50
S23	58	tamura-naoyuki.in.	US-PGPUB; USPAT	OR	ON	2005/04/16 20:08
S24	214	c23c016$.ipc. and ((position$3 align$3) with (sens$3 detect$3 monitor$3 observ$5))	EPO; JPO; DERWENT	OR	ON	2003/12/18 19:36
S28	20	(US-20030023343-$ or US-20030168173-$ or US-20040074603-$ or US-20040151574-$).did. or (US-4507078-$ or US-4618292-$ or US-4643579-$ or US-4654106-$ or US-4819167-$ or US-4836733-$ or US-5452521-$ or US-5483138-$ or US-5512320-$ or US-5814196-$ or US-5917601-$ or US-5980194-$ or US-6166509-$ or US-6368183-$ or US-6370793-$ or US-6553280-$).did.	US-PGPUB; USPAT	OR	ON	2004/11/10 17:39
S29	65	tamura-naoyuki.in.	US-PGPUB; USPAT	OR	ON	2005/04/16 20:08
S30	2	10/218,406	US-PGPUB; USPAT	OR	ON	2005/10/17 16:00
S31	484	(414/805.ccls. 414/217.ccls.) and ((wafer substrate semiconductor workpiece) with (align$4 orient$4))	US-PGPUB; USPAT	OR	ON	2005/10/16 20:05
S32	74	(414/805.ccls. 414/217.ccls.) and ((wafer substrate semiconductor workpiece) with (align$4 orient$4) with (sens$4 detect$4 measur$4 observ$4))	US-PGPUB; USPAT	OR	ON	2005/10/16 20:05
S33	105	(414/805.ccls. 414/217.ccls.) and ((wafer substrate semiconductor workpiece) with (align$4 orient$4) with (sens$4 detect$4 measur$4 observ$4 control$4))	US-PGPUB; USPAT	OR	ON	2005/10/16 20:05
S34	46	(414/805.ccls. 414/217.ccls.) and ((wafer substrate semiconductor workpiece) with (align$4 orient$4) with (sens$4 detect$4 measur$4 observ$4 control$4) with (transfer$4 translat$4 convey$4 mov$4))	US-PGPUB; USPAT	OR	ON	2005/10/16 20:06
S35	5	("5706930").URPN.	USPAT	OR	ON	2005/10/16 20:15
S36	45	("3907439" | "3945505" | "4024944" | "4148344" | "4201378" | "4228886" | "4449885" | "4457664" | "4466073" | "4507078" | "4523985" | "4559451" | "4635373" | "4647266" | "4698511" | "4705951" | "4720635" | "4744713" | "4765793" | "4770590" | "4789294" | "4818169" | "4819167" | "4833790" | "4836733" | "4880348" | "4907035" | "5044752" | "5162642" | "5194743" | "5239182" | "5483138" | "5706201" | "5706930" | "5721607" | "5740062" | "5768125" | "5822213" | "5870488" | "5905850" | "5917601" | "5980194" | "5995234" | "6198976" | "6327517").PN.	US-PGPUB; USPAT; USOCR	OR	ON	2005/10/16 20:16
S37	56	("5483138").URPN.	USPAT	OR	ON	2005/10/16 20:29